

# Research on Overcurrent Interruption Capability and Influencing Factors of SiC MOSFETs in DCCBs

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## ➤ Introduction

- ❑ Flexible DC grids' low impedance causes rapidly rising fault currents, necessitating DCCBs for millisecond-level fault interruption.
- ❑ Power modules are the core component of high-voltage DCCB.



### Flexible direct current transmission

- Flexible Dispatch
- Efficient Transmission
- Facilitated Renewable Energy Grid Integration



### DC circuit breakers

- Short switching time
- High on-state current
- High withstand voltage



### Power modules

- High voltage and high current
- Fully-controlled and high reliability
- High-temperature capability and low losses



## ➤ Introduction

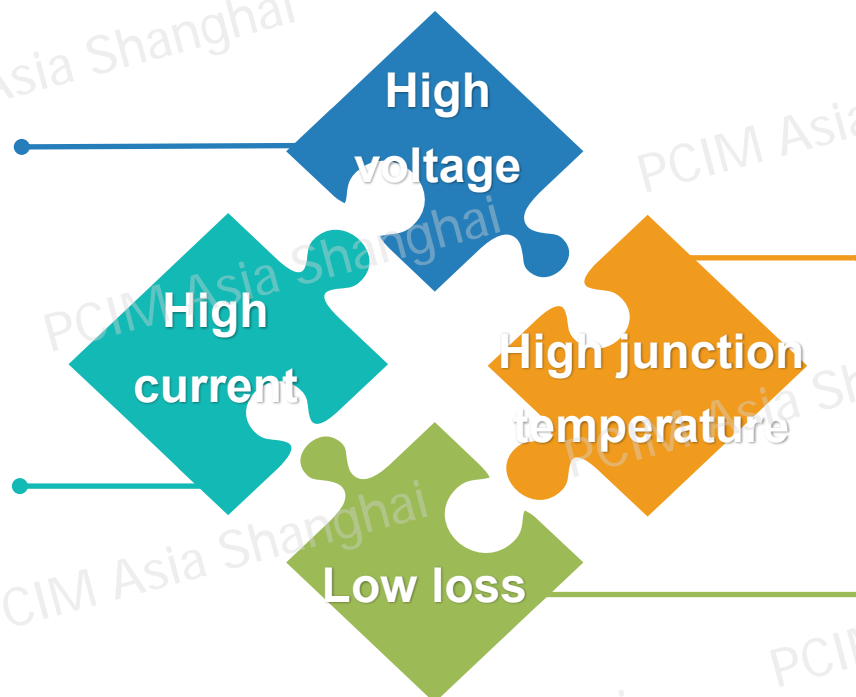
- ❑ Silicon-based devices suffer from low efficiency and bulkiness, failing practical new electricity system. This necessitates next-generation power devices with **higher voltage/current capabilities, elevated junction temperatures, and lower losses** for essential system support.

### ■ Higher voltage

Reduce the number of devices in series and optimizes the topology.

### ■ Higher current

Improve the fault traversal ability and reliability of the system.



### ■ Higher junction temperature

Simplify the equipment's heat dissipation system and reduce overall system costs.

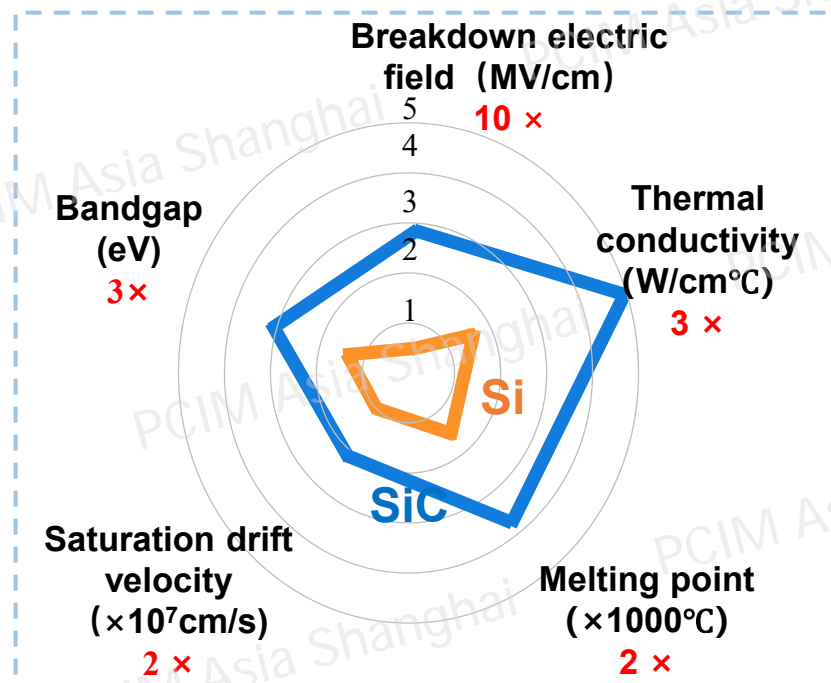
### ■ Lower loss

Reduce system heating; Improve the efficiency of system transmission and conversion.

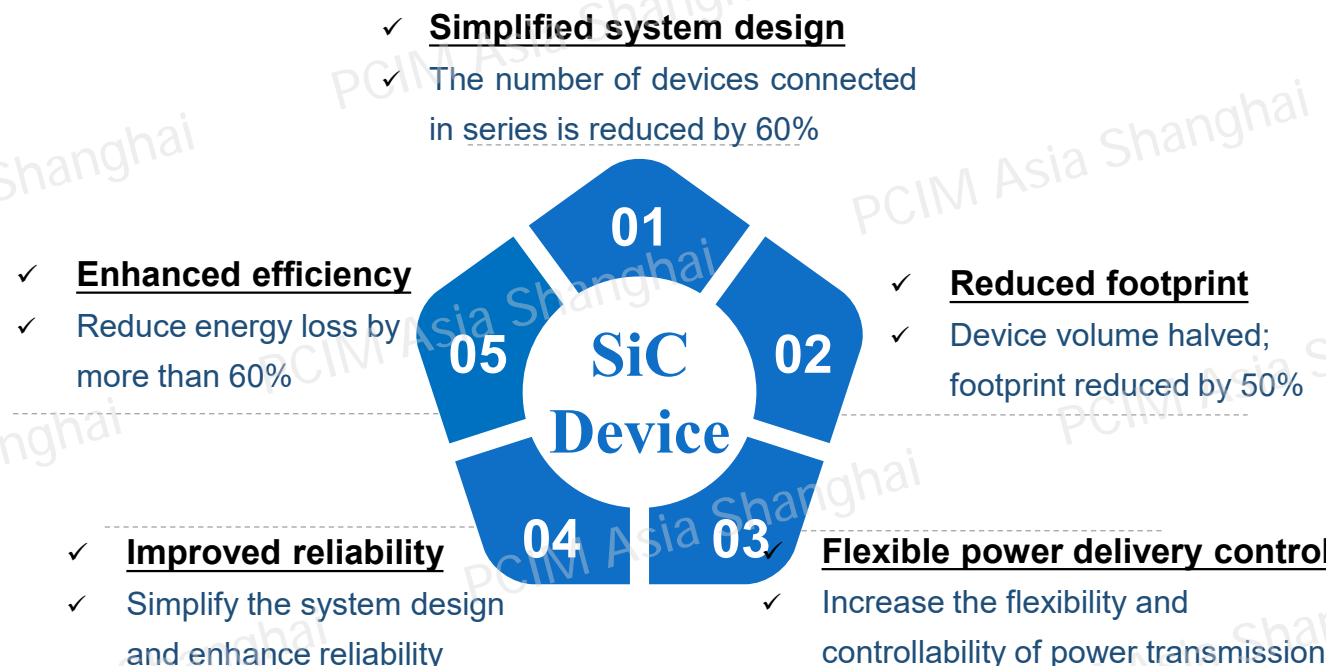
**Advanced Requirements for Power Devices in High-Efficiency Power Electronic Transformers**

## ➤ Introduction

- ❑ SiC's superior material properties enable high-voltage, high-temp, low-loss power devices vs. Si.
- ❑ SiC devices increase DCCB efficiency and power density, reduce volume, and strengthen technical advantages for future DC grids.



**SiC vs. Silicon: Property Comparison**

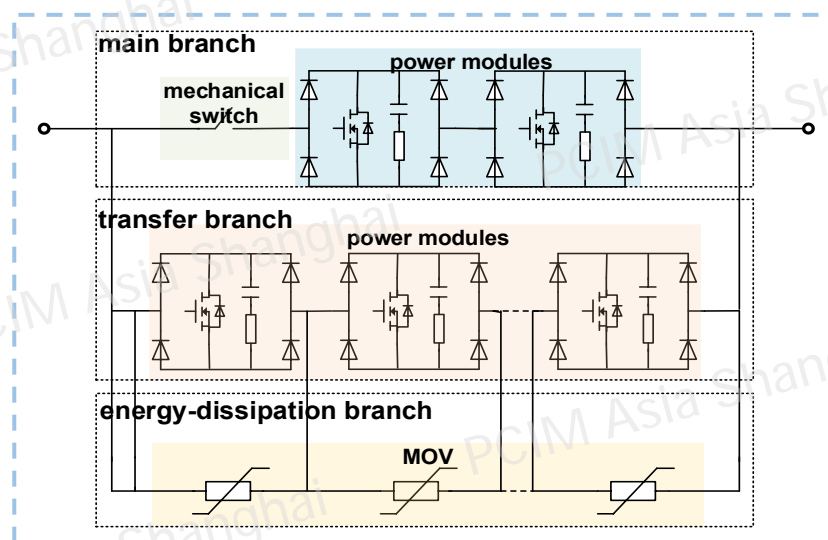


**SiC-Enabled DCCBs**

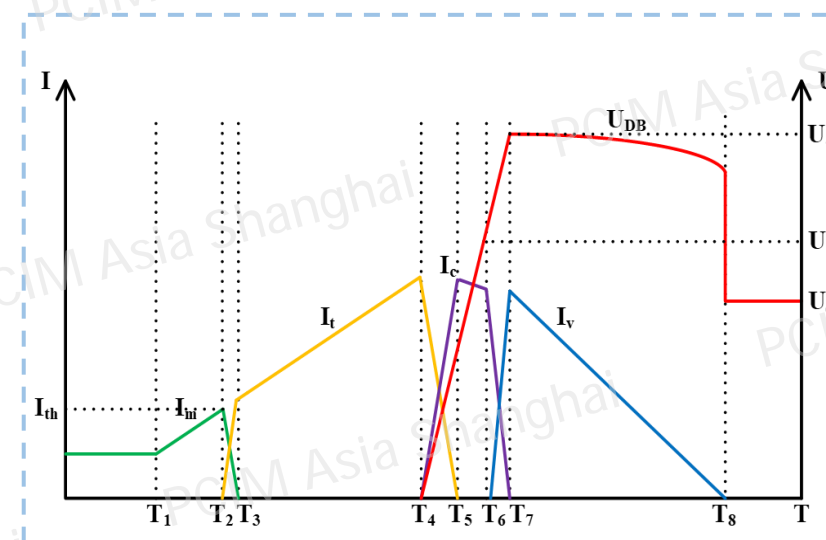
# ➤ Overcurrent Interruption Capability Comparison

## ◆ Topology and Principles of Hybrid DCCBs

- ❑ Main Branch: Fast mechanical switch + few power modules (**conducts load current**).
- ❑ Transfer Branch: Multi-level series power modules (**carries/interrupts fault current**).
- ❑ Energy-Dissipation Branch: Series MOVs (**limits overvoltage, absorbs inductive energy**).



Topology of the hybrid DCCB

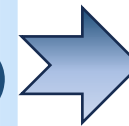


Principle of the hybrid DCCB

# ➤ Overcurrent Interruption Capability Comparison

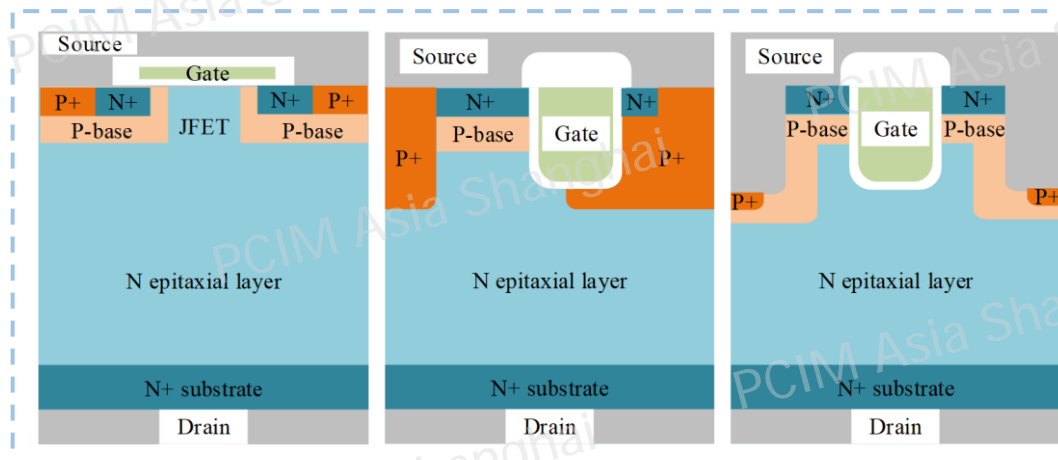
## ◆ Experimental Setup

- ✓ Planar (1200 V/ 57 A/ 39 mΩ)
- ✓ Asymmetric trench (1200 V/ 55 A/ 40 mΩ)
- ✓ Double trench (1200 V/ 55 A/ 40 mΩ)

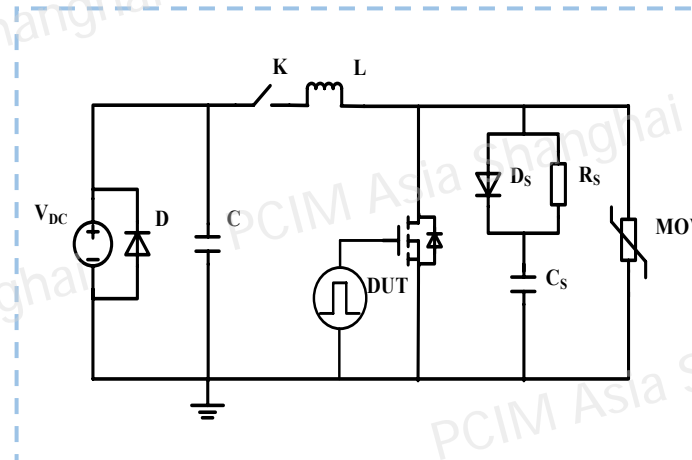


## Power devices in DCCB Transfer Branch :

- ✓ Withstand above-rated short-circuit currents (ms)
- ✓ Conduct → interrupt sequence
- ✓ most demanding tests



Cell structures of three DUTs



Experiment circuit



Experiment platform

# ➤ Overcurrent Interruption Capability Comparison

## ◆ Comparison results of overcurrent interruption capability

$U_{ds} \uparrow$  with  $I_{ds} \uparrow$  &  $T_j \uparrow \longleftrightarrow T_j \uparrow$  with  $I_{ds} \uparrow$  &  $U_{ds} \uparrow$

Distinct knee point = Linear  $\rightarrow$  Saturation transition



Key Limiters of OC:

$R_{on}$ ,  $I_{sat}$

$$P_{max} = \frac{T_{jmax} - T_c}{R_{th}} \quad (1)$$

$$R_{th} = \frac{d}{\lambda A} \quad (2)$$

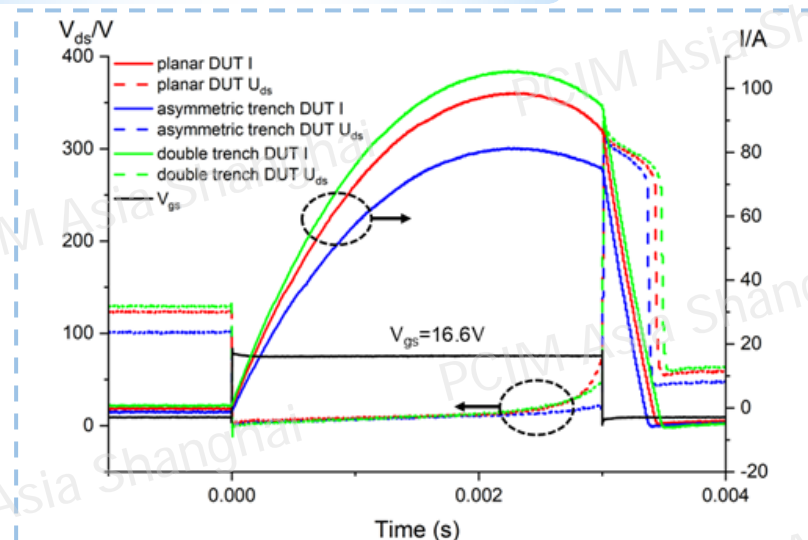


Chip area  $\uparrow$

overcurrent  $\uparrow$

Trench structure

overcurrent density  $\uparrow$



DUTs	$I_{rated}$ (A)	$I_{max}$ (A)	$I_{norm}$	$I_{avg}$ (A/mm <sup>2</sup> )
Planar	57	99.2	1.74	11.69
Asymmetrical	55	83.4	1.51	15.58
Double	55	106.1	1.92	17.32

The comparison of the maximum overcurrent of the three DUTs



# ➤ Overcurrent Interruption Capability Comparison

## ◆ Comparison results of overcurrent interruption capability

### SiC MOSFET OC Comparison (DCCB): Planar vs. Asymm. Trench vs. Double. Trench

#### ✓ Overcurrent density Ranking

- ① Double Trench: Highest OC density
- ② Asymmetric Trench
- ③ Planar

→ Trench advantage: Channel density ↑,  $R_{ON,sp}$  ↓

#### ✓ Turn-off Capability Ranking

- ① Double Trench: Superior performance
- ② Planar
- ③ Asymmetric Trench: Thermal bottleneck

→ (Small active area → heat concentration)

#### ✓ Fundamental Limiters

⚡  $R_{ON}$  &  $I_{sat}$  → (Primary constraints for SiC MOSFET OC capability)

# ➤ Factors Influencing Overcurrent Interruption Capability

- ❑ Enhancing  $I_{sat}$  & reducing  $R_{on}$  to analyze max turn-off overcurrent
- ❑ Subsequently evaluating gate voltage, environment Temperature and on-state duration effects on OC interruption capability under DCCB conditions.

$R_{on}$

$$R_{ON} \sim R_{ch} + R_{FET} + R_{Drift} \quad (4)$$

$$R_{ch} = \frac{LW}{2\mu_n C_{ox}} \frac{1}{V_{gs} - V_{th}} \quad (5)$$

$$R_{FET} = \frac{\rho_{JFET} \chi_{jP} W}{\alpha} \quad (6)$$

$$R_{Drift} = \frac{L_d}{q\mu_{n,d} N_d A_d} \quad (7)$$

$I_{sat}$

$$I_{sat} = \frac{W\mu_n C_{ox}}{2L} (V_{gs} - V_{th})^2 \quad (3)$$

**Influence Factors:**

**Gate Drive Voltage**

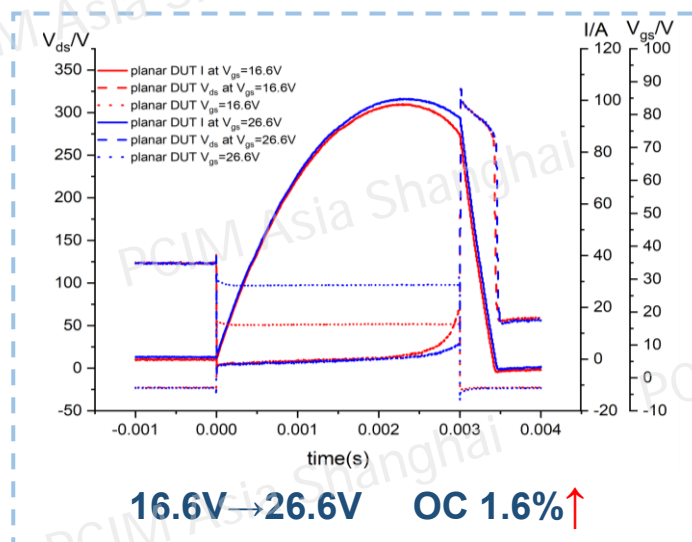
**Environment Temperature**

**On-State Duration**

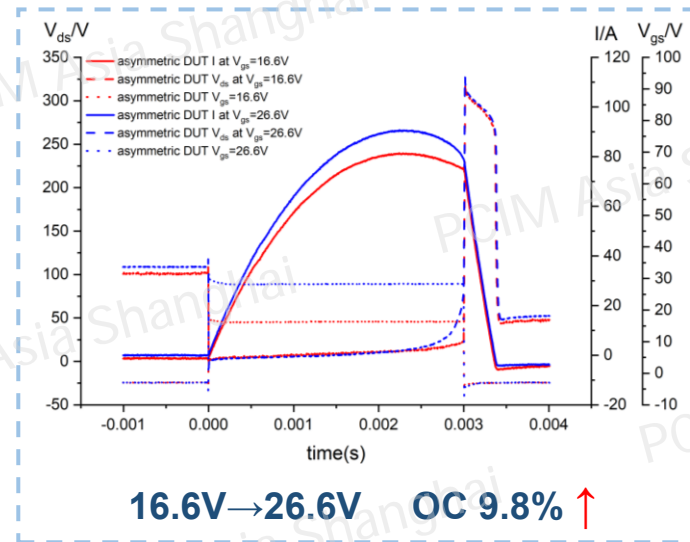
# ➤ Factors Influencing Overcurrent Interruption Capability

## ◆ Influence of Gate Drive Voltage

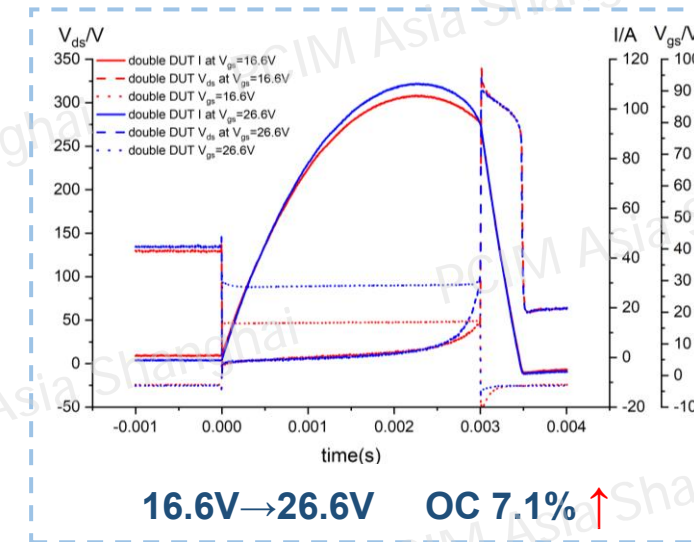
- ❑ Planar DUT: Thermal failure → Gate-source short (**thin gate oxide**)
- ❑ Trench DUT: Higher sensitivity to  $V_{gs}$  (trench structure & process)
- ✓ **Dry etching** → Interface defects  $R_{CH} \uparrow$   $I_{sat} \downarrow$
- ✓  $V_{gs} \uparrow$ : Inversion charge accumulation  $R_{CH} \downarrow$  contribution to  $R_{on}$
- ✓ **Higher trench density** → Key to  $I_{sat} \uparrow$



Planar DUT



Asymmetric trench DUT

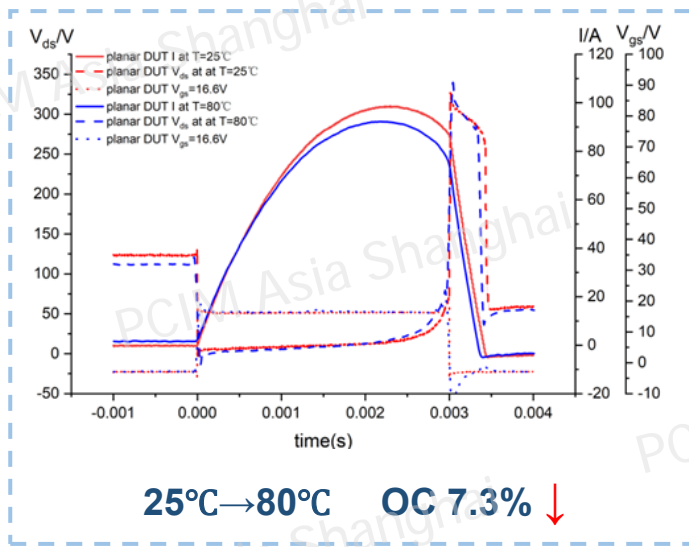


Double trench DUT

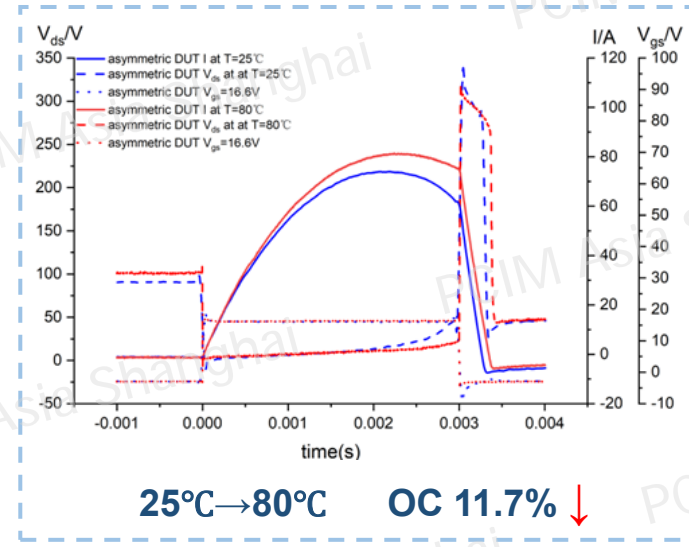
# ► Factors Influencing Overcurrent Interruption Capability

## ◆ Influence of Environment Temperature

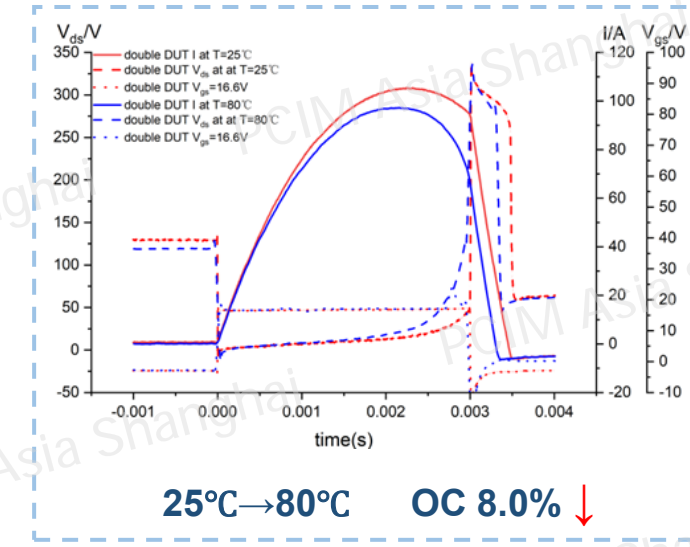
- $\mu_n$ -T Relationship: High T (>350°C): **Deep traps emission** ↓ + **Phonon scattering** ↑ →  $\mu_n$  ↓ →  $R_{ON}$  ↑,  $I_{sat}$  ↓
- Environment Temperature Influence :  $T_c$  ↑ → Earlier thermal limit → OC capability ↓ (Worst in asymmetric DUT: smallest active area → heat accumulation)



Planar DUT



Asymmetric trench DUT



Double trench DUT



# ➤ Factors Influencing Overcurrent Interruption Capability

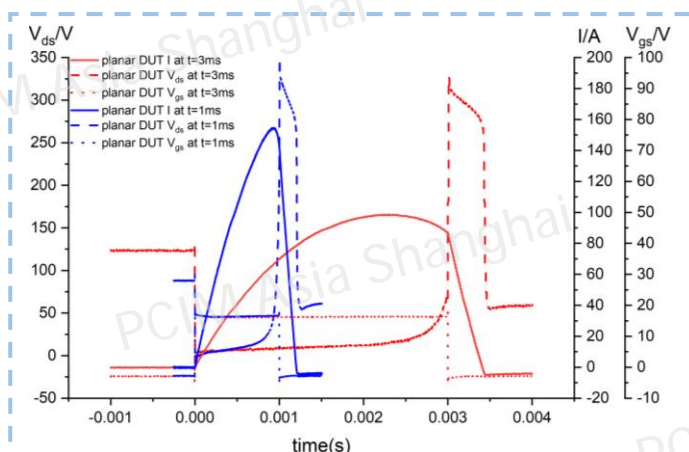
## ◆ Influence of On-State Duration

□ On-State Duration  $\uparrow \rightarrow$  Energy accumulation  $\rightarrow T_j \uparrow \rightarrow$  Latch-up effect  $\rightarrow$  Failure

✓ (Root cause = **Temperature**  $\rightarrow$  Matches external  $T_c$  trend;

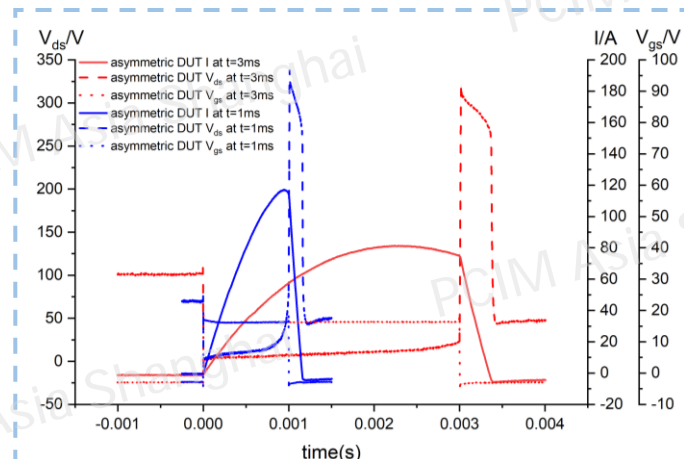
$$E = \int_0^{t_{on}} V_{ds} I_{ds} dt \quad (8)$$

✓ Short on-State duration impact  $>$  external  $T_c \rightarrow$  ⚡ Short-pulse operation: Inadequate heat dissipation  $\rightarrow$  Identifies **internal heating as decisive factor**



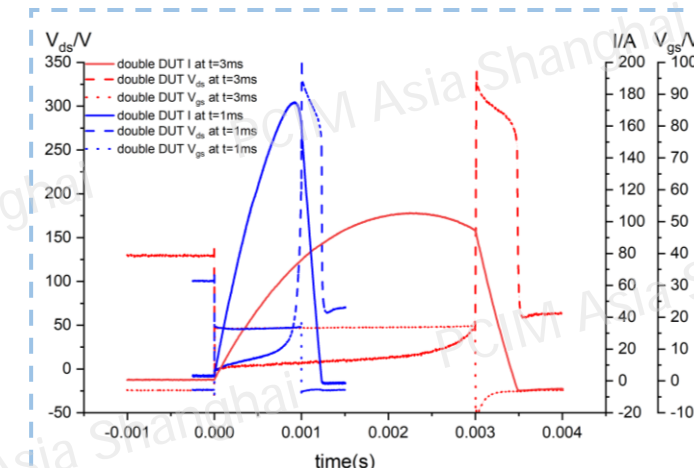
3ms  $\rightarrow$  1ms OC 58.3%  $\uparrow$

Planar DUT



3ms  $\rightarrow$  1ms OC 40.3%  $\uparrow$

Asymmetric trench DUT



3ms  $\rightarrow$  1ms OC 64.9%  $\uparrow$

Double trench DUT

# ➤ Factors Influencing Overcurrent Interruption Capability

SiC MOSFET OC Comparison (DCCB): Planar vs. Asymm. Trench vs. Symm. Trench | 3 Key Factor

Gate Drive  
Voltage

Environment  
Temperature

3  
Key Factor

On-State  
Duration

- ✓ Trench DUTs: Significant OC ↑ with  $V_{gs}$  ↑ (trench structure & process)
- ✓ Planar DUT: Gate-source short risk (Thin oxide limitation)

- ✓ All DUTs: OC ↓ with  $T_c$  ↑ (Mechanism: with  $T_c$  ↑, Earlier thermal limit:  $R_{ON}$  ↑,  $I_{sat}$  ↓)
- ✓ Critical Case: Asymmetric trench (smallest active area : Thermal accumulation hotspot)

- ✓ Key Finding:  $t_{on}$  ↓ → OC ↑↑ capability (Outperforms ambient  $T_c$  mitigation)
- ✓ Root Cause: Internal heat spike > ambient heating (Inadequate heat dissipation in such a short period of time)
- ⚠ DCCB Design Rule: Minimize  $t_{on}$

## ➤ Conclusion

- **Current Conduction Density: Double trench > Asymmetric trench > Planar (trench designs boost channel density & reduce  $R_{ON,sp}$ )**
- **Overcurrent Interruption Capability: Double trench > Planar > Asymmetric trench (Asymmetric trench limited by smaller active area & concentrated heat dissipation)**
- **Increasing gate voltage, reducing environment temperature, and shortening on-state duration enhance performance by reducing  $R_{ON}$  and boosting  $I_{sat}$  to varying degrees.**
  - Gate drive voltage boosts trench DUTs' overcurrent interruption via structural advantages, while planar DUTs face gate-source short-circuit limitations.
  - As the environment temperature increases, the overcurrent interruption capability of all DUTs declines due to the faster rise in DUTs' temperature into the high-temperature range, which increases  $R_{ON}$  and reduces  $I_{sat}$ .
  - On-state time enhances interruption capability (surpassing temperature effects) with internal loss-induced thermal rise as decisive constraint. Shortening the on-state duration is critical for improving performance.



# Thank You!

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